										Page	1 of 1
Form PTO-1449 (modified)					Atty. Docket No. Se				l No.		
			2000.071900/TT4369 Unknown								
		nd Publications f	Applicant								
Inf	FORMATION	ON DISCLOSURE	Kevin R. Lensing					70			
	Alse	several sheets if neces	comi)	Filing Date:			Group:		55		
							Unknown &				
1					Patent Documents			Other Art			
	Dec 1	uge 1		Se	e Page 1		_		ee Page 1	<u> </u>	
										<u> </u>	三
	r		U.S. Pa	ater	nt Docume	ents					
Exam. Init.	Ref. Des.	Document Number	Date		Name	Class		Sub Class	Filing Date of App.		of
KCK	A1	5,867,276	2/2/99	McNeil et al.		356		445			-
KCK	A2	5,877,276	3/2/99	3/2/99 Borden		356		376			
KCK	A3	5,880,838	3/9/99	3/9/99 Marx et al.		356		351			
KCK	A4	6,081,334	334 6/27/00 G		imbergen <i>et al</i> .	356		357		<u> </u>	
	A5										
			Foreign I	Pate	ent Docun	nents					
Exam. Init.	Ref. Des.	Document Number	Date		Country	Class		Sub lass		slation s/No	1
	B1						\dashv				
	B2						+				—_
	В3										
C	Other A	Art (Includi	ng Autho		Title, Date	Perti	nen	t Pag	es. Et	c.)	
Exam. Init.	Ref. Des.		Citation								
	Cl					· · · · · ·					
	C2						* 1				
	C3		·								

EXAMINER: **DATE CONSIDERED:** Form PTO-1449' (modified)

Atty. Docket No. 2000.071900/TT4369 Serial No. 09/897,205

List of Patents and Publications for Applican

Kevin R. Lensing

Applicant

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Filing Date: July 2, 2001 Group: 2877

U.S. Patent Documents See Page 1

Foreign Patent Documents See Page 1

Other Art See Page 1

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
KCK	Al	5,629,772	5/13/97	Ausschnitt	356	372	
KCK	A2	5,655,110	8/05/97	Krivokapic et al.	395	500	
KCK	A3	5,773,174	6/30/98	Koizumi et al.	430	30	
KCK	A4	5,926,690	7/20/99	Toprac et al.	438	17	
	A 5						

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
	B1						
	B2						
	В3						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
KCK	Cl	Hankinson et al., "Integrated Real-time and Run-to-Run Control of Etch Depth in Reactive Ion Etching," Mar. 13, 1996, pp. 1-17
KCK	C2	Boning et al., "Practical Issues in Run by Run Process Control," 1995 IEEE/SEMI Advanced Manufacturing Conference, 1995, pp. 201-208
KCK	C3	Zafiriou et al., "Nonlinear Model Based Run-to-Run Control for Rapid Thermal Processing with Unmeasured Variable Estimation," 187th ECS Meeting, Reno, NV, May 1995
KCK	C4	Boning et al., "Run by Run Control of Chemical-Mechanical Polishing," IEEE/CHMT International Electronics Manufacturing Technology Symposium, Austin, TX, Oct. 2-4, 1995
KCK	C5	Smith et al., "Compensating for CMP Pad Wear Using Run by Run Feedback Control," VMIC, Santa Clara, CA, June 18-20, 1996
KCK	C6	Sachs et al., "Process Control System for VLSI Fabrication," IEEE Transactions on Semiconductor Manufacturing, April 5, 1990, pp. 1-31

Examiner:	Kun	rike	<i>C</i> .	Koyama	ノ

DATE CONSIDERED:

EXAMINER: INITIAL IF REFERENCE CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.

				•••				
Examiner:	Kus	niko	C	Koyama	N	DATE CONSIDERED:	11//3	102

C3

EXAMINER: INITIAL IF REFERENCE CONSIDERED WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.